



UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: NISHIUCHI, Takeshi et al.

Group Art Unit: 1763

Serial No.: 09/813,129

Examiner: BUEKER, Richard R.

Filed: March 21, 2001

P.T.O. Confirmation No.: 1444

For: DEPOSITED-FILM FORMING APPARATUS

AMENDMENT UNDER 37 CFR §1.111

Commissioner for Patents
Washington, D.C. 20231

January 24, 2003

Sir:

In response to the Office Action dated September 24, 2002, please amend the above-identified application as follows:

IN THE CLAIMS:

Please cancel non-elected Claims 7 and 8 without prejudice or disclaimer.

Please amend Claims 1, 4 and 5, as follows:

1. (Amended) A deposited-film forming apparatus comprising an evaporating section for at least one depositing material selected from the group consisting of aluminum, zinc, tin and magnesium and an alloy containing at least one of these metal components, and a tubular barrel formed of a mesh net for accommodation of rare earth metal-based permanent magnets, on each of the surfaces of which a depositing material is to be deposited, said evaporating section and said tubular barrel being mounted in a vacuum-treating chamber, wherein said tubular barrel is supported circumferentially outside a horizontal rotational axis of a support member rotatable about said

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